

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):	Ishiduka et al.	Examiner:	Unassigned
Application No.:	Unassigned	Group Art Unit:	Unassigned
Confirmation No:	Unassigned	Docket:	1608-7 PCT/US
Filed:	Herewith	Dated:	September 5, 2006
For:	POSITIVE-TYPE RESIST COMPOSITION FOR LIQUID IMMERSION LITHOGRAPHY AND METHOD FOR FORMING RESIST PATTERN		

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Dated: September 5, 2006 Label No. EV 881318080US
I hereby certify that on the date indicated above I
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22313-1450 by EXPRESS MAIL POST OFFICE to ADDRESSEE service.

Barbara Thomas
Name (Print)

(Signature)

INFORMATION DISCLOSURE STATEMENT

Sir:

In order to fulfill the requirements of candor and good faith set forth in 37 C.F.R. §1.56, Applicants submit herewith the following Information Disclosure Statement in accordance with the provisions of 37 C.F.R. §1.97 and §1.98. It is understood that the information provided herein is solely for the purpose of fulfilling Applicants' obligations under the law and should not be construed as nor is it intended to be an admission of prior art.

Pursuant to the PTO's waiver under 37 C.F.R. §1.98(a)(2)(ii), no copies of the granted U.S. patent and/or the published U.S. patent application references listed on the

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attached Form PTO-1449 are being submitted herewith.

This Statement is also being filed concurrently with the application and is timely pursuant to 37 C.F.R. §1.97.

The Commissioner is hereby authorized to charge payment of any additional fees associated with this communication, or credit any overpayment, to Deposit Account No. 08-2461. Such authorization includes authorization to charge fees for extensions of time, if any, under 37 C.F.R § 1.17 and also should be treated as a constructive petition for an extension of time in this reply or any future reply pursuant to 37 C.F.R. § 1.136.

If the Examiner has any questions or comments relating to the present application, he or she is respectfully invited to contact Applicants' attorney at the telephone number set forth below.

Respectfully submitted,



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FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE (Rev. 2-32) PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	ATTY. DOCKET NO. 1608-7 PCT/US	10/591718 SERIAL NO. Unassigned
	APPLICANT Ishiduka et al.	CONFIRMATION NO. Unassigned
	FILING DATE Herewith	GROUP Unassigned

U.S. PATENT PUBLICATIONS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
/C.J./	2003/ 0078352	04/24/03	Miyazawa et al.			
/C.J./	2003/ 0224283	12/04/03	Allen et al.			

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION	
						YES	NO
/C.J./	WO 2004/ 088429	10/14/04	PCT				
/C.J./	WO 99/ 49504	09/30/99	PCT				
/C.J./	EP 1610178	12/28/05	EPO				
/C.J./	JP 2005- 055890	03/03/05	Japan (abstract)				
/C.J./	JP 2004- 046098	02/12/04	Japan (abstract)				
/C.J./	JP 2004- 069981	03/04/04	Japan (abstract)				
/C.J./	JP 2003- 040840	02/13/03	Japan (abstract)				
/C.J./	JP 2002- 169287	06/14/02	Japan (abstract)				

EXAMINER

DATE CONSIDERED

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/C.J./		JP 11-176727	07/02/99	Japan (abstract)				
/C.J./		JP 62-065326	03/24/87	Japan (abstract)				

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

/C.J./		Hoffnagle et al.; Liquid immersion deep-ultraviolet interferometric lithography; Journal of Vacuum Science & Technology B; Vol. 17, No. 6; American Vacuum Society; Nov/Dec 1999; pp. 3306-3309
/C.J./		Switkes et al.; Immersion Lithography at 157 nm; Journal of Vacuum Science and Technology B., Vol. 19, No. 6; American Vacuum Society, Nov/Dec 2001; pp 2353-2356
/C.J./		Switkes et al.; Resolution enhancement of 157 nm Lithography by Liquid Immersion; Proceedings of SPIE Vol. 4691; 2002; pp. 459-465

EXAMINER /Connie Johnson/ DATE CONSIDERED 07/20/2008

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